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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE
(Case No. 207.010-US)

In the Application of: **LUTZ ET AL.**

Serial No: **10/698,268**

Filed: **OCTOBER 31, 2003**

Title: **ANTI-STICTION TECHNIQUE FOR THIN FILM
AND WAFER-BONDED ENCAPSULATED
MICROELECTROMECHANICAL SYSTEMS**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

)
) Group
) Art Unit: **2814**
)
) Before
) Examiner

I hereby certify that this correspondence
is being deposited with the United States
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Patents, P.O. Box 1450, Alexandria, VA
22313-1450 on June 10, 2004

Michiko Sites
(person signing this certificate)

Michiko Sites
Signature

SECOND INFORMATION DISCLOSURE STATEMENT

Dear Sir:

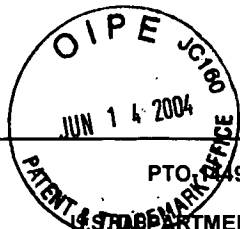
Submitted herewith is one (1) sheets of a modified Form PTO-1449. A copy of each
document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these
documents formally of record with the initial Office Action.

Respectfully submitted,

Date: June 10, 2004

Neil A. Steinberg
Reg. No. 34,735
650-968-8079



Sheet 1 of 1

PTO 249 (Modified) DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO. 207.010-US	SERIAL NUMBER 10/698,258
	APPLICANT(S) Lutz et al.	
	FILING DATE October 31, 2003	GROUP ART UNIT 2814

U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLAS S	SUB CLAS S	FILING DATE
	4,849,071	7/1989	Evans et al.			
	4,945,769	8/1990	Sidner et al.			
	5,445,991	8/1995	Lee			
	5,470,797	11/1995	Mastrangelo			
	5,616,514	4/1997	Muchow et al.			
	6,521,508	2/2003	Cheong et al.			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLAS S	SUB CLAS S	TRANSLATION YES/NO

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	"Chemical Vapor Deposition of Fluoroalkylsilane Monolayer Films for Adhesion Control in Microelectromechanical Systems", Mayer et al., J. Vac. Sci. Technol. B 18(5), Sept/Oct 2000, pp.2433-2440

EXAMINER	DATE CONSIDERED
EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.	